



PATENT
P56138PCT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

MYOUNG-JIN KIM

Serial No.: 09/582,843

Examiner: AHMED, SAMIR ANWAR

Filed: 5 July 2000

Art Unit: 2623

For: METHOD FOR INSPECTING INFERIORITY IN SHAPE

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MAY 06 2004

Technology Center 2600

INFORMATION DISCLOSURE STATEMENT

Mail Stop: Issue Fee
Commissioner for Patents
P.O.Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F.R. §1.56, and §§1.97 and 1.98 as amended, Applicant cites, describes, and provides copies of the following art references:

U.S. PATENT REFERENCE:

- U.S. Patent No. 5,339,093 to Kumagai *et al.*, entitled LIQUID CRYSTAL PANEL INSPECTION METHOD, issued on 16 August 1994.

FOREIGN PATENT REFERENCE:

- Canadian Patent No. 2,249,265 to Pearson *et al.*, entitled METHOD, APPARATUS AND SYSTEM FOR VERIFICATION OF PATTERNS, issued on 2 October 1997.
- World Intellectual Property Organization International Patent Publication WO97/36260 of E.C. Pearson, *et al.* Dated 25 March 1996.

OTHER DOCUMENTS:

- *Canadian Office Action* of the Canadian Patent Application No. 2,317,803 (dated 9 January 2004).

DISCUSSION


As noted in the Office Action issued by the Canadian Intellectual Property Office on the 9th of January 2004 in applicant's corresponding Canadian Patent Application No. 2,317,803 corresponding to applicant's above-captioned U.S. Patent Application, Kumagai *et al.* U.S.'093 relates to the present invention which makes it possible for unskilled to inspect the total surface of a liquid crystal panel accurately in short time. "Before the inspection, a unit area of an image without defect is selected from a liquid crystal panel to be inspected. The upper limit reference pattern and the lower limit reference pattern are generated and the brightness of each pixel of the upper limit and the lower limit reference pattern is compared with the brightness of a pattern to be inspected."

Pearson *et al.* CA'265, and Pearson *et al.* WO'260 relates to "a method and apparatus for verifying the establishment of a pattern including means for storing a template of the pattern, means for acquiring an image of the established pattern, a first image processing means to alter at least one of said template and acquired images to produce at least two resulting images, comparison means to compare the two resultant images with each other of said template and acquired images and means to evaluate the results."

The citation of the foregoing references is not intended to constitute an assertion that other or more relevant art does not exist. Accordingly, the Examiner is requested to make a wide-ranging and thorough search of the relevant art.

Pursuant to 37 C.F.R. §1.97(c)(2), the fee set forth under 37 C.F.R. §1.17(p) of \$180.00 accompanies this Information Disclosure Statement. Should the check become lost, be deficient in payment, or should other fees be incurred, the Commissioner is authorized to charge Deposit Account No. 02-4943 of Applicant's undersigned attorney in the amount of such fees.

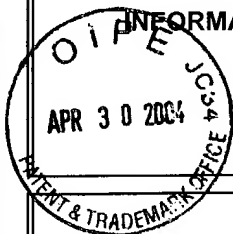
Respectfully submitted,


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INFORMATION DISCLOSURE STATEMENT

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SERIAL NUMBER 09/582,843

DOCKET NO. P56138PCT

APPLICANT

MYOUNG-JIN KIM

FILING DATE 5 July 2000

GROUP

2623

U.S. PATENT DOCUMENTS

EXAMINER	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,339,093	08/94	Kumagai <i>et al.</i>			

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FOREIGN PATENT DOCUMENTS

TRANSLATION

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	YES	NO
	CA 2,249,265	10/97	CANADA			Abstract	
	WO 97/36260	03/96	EUROPE			Abstract	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

	Canadian Office Action of the Canadian Patent Application No. 2,317,803 (dated 9 January 2004).

EXAMINER:

DATE CONSIDERED:

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP §609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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